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Amendments to the Claims:In the claims:

Please AMEND claims 1, 6, 10, 21, 26 and 28, CANCEL claim 5 without prejudice and ADD claim 29 such that the pending claims will read as follows:

Claim 1 (Currently amended): A mounting assembly for a wafer-scrubber brush, comprising:

a mounting member adapted to be mounted to a wall of a wafer scrubbing device;

a bearing secured to the mounting member; and

a brush support rotatably mounted on the bearing and having an outer end that includes a contact surface adapted to contact a brush mandrel, the contact surface having a spherical profile so as to form a spherical joint between the brush mandrel and the brush support that compensates for mounting assembly misalignment during brush mounting.

Claim 2 (Original): The mounting assembly of claim 1, wherein the contact surface has a convex shape adapted to mate with a concave portion of the brush mandrel.

Claim 3 (Original): The mounting assembly of claim 1, wherein the contact surface has a concave shape adapted to mate with a convex portion of the brush mandrel.

Claim 4 (Original): The mounting assembly of claim 1, further comprising a spring enclosed in the brush support and adapted to bias the outer end of the brush support against the brush mandrel.

Claim 5 (Canceled).

Claim 6 (Currently amended): A mandrel adapted to mount a wafer-scrubber brush, the mandrel comprising a generally cylindrical body, the body having an end adapted to couple to a mounting support, the end including a contact surface adapted to contact the mounting support, the contact surface having a spherical profile so as to form a spherical joint between the mandrel and the mounting support that compensates for mounting assembly misalignment during brush mounting.

Claim 7 (Original): The mandrel of claim 6, wherein the contact surface has a concave shape adapted to mate with a convex portion of the mounting support.

Claim 8 (Original): The mandrel of claim 6, wherein the contact surface has a convex shape adapted to mate with a concave portion of the mounting support.

Claim 9 (Original): The mandrel of claim 6, further comprising a spring mounted in the body and adapted to bias the end against the mounting support.

Claim 10 (Currently amended): A wafer scrubbing device, comprising:

    a first mounting assembly; and  
    a brush assembly mounted to the first mounting assembly;  
    the first mounting assembly and the brush assembly having respective joint portions that mate together to form a first spherical joint that compensates for mounting assembly misalignment during brush assembly mounting.

Claim 11 (Original): The wafer scrubbing device of claim 10, wherein the first mounting assembly includes a spring adapted to bias the joint portion of the first mounting assembly toward the joint portion of the brush assembly.

Claim 12 (Original): The wafer scrubbing device of claim 10, wherein the brush assembly includes a spring adapted to bias the joint portion of the brush assembly toward the joint portion of the first mounting assembly.

Claim 13 (Original): The wafer scrubbing device of claim 10, wherein the joint portion of the first mounting assembly is convex and the joint portion of the brush assembly is concave.

Claim 14 (Original): The wafer scrubbing device of claim 10, wherein the joint portion of the first mounting assembly is concave and the joint portion of the brush assembly is convex.

Claim 15 (Original): The wafer scrubbing device of claim 10, further comprising a second mounting assembly to which the brush assembly is mounted, the second mounting assembly and the brush assembly having respective joint portions that mate together to form a second spherical joint.

Claim 16 (Original): The wafer scrubbing device of claim 15, wherein at least one of the mounting assemblies includes a spring adapted to bias the joint portion of the respective mounting assembly toward a corresponding joint portion of the brush assembly.

Claim 17 (Original): The wafer scrubbing device of claim 15, wherein the brush assembly includes a spring adapted to bias one

of the joint portions of the brush assembly toward the joint portion of a corresponding one of the brush assemblies.

Claim 18 (Original): The wafer scrubbing device of claim 15, wherein the joint portions of the mounting assemblies are convex and the joint portions of the brush assembly are concave.

Claim 19 (Original): The wafer scrubbing device of claim 15, wherein the joint portions of the mounting assemblies are concave and the joint portions of the brush assembly are convex.

Claim 20 (Original): The wafer scrubbing device of claim 15, wherein the joint portion of the first mounting assembly is convex, the joint portion of the second mounting assembly is concave, the joint portion of the brush assembly corresponding to the first mounting assembly is concave, and the joint portion of the brush assembly corresponding to the second mounting assembly is convex.

Claim 21 (Currently amended): A mandrel adapted to mount a wafer-scrubber brush, the mandrel comprising a generally cylindrical body, the body having a first end adapted to couple to a first mounting support and a second end adapted to couple to a second mounting support, the first end including a first contact surface adapted to contact the first mounting support, the first contact surface having a spherical profile so as to form a spherical joint between the first end of the mandrel and the first mounting support that compensates for mounting assembly misalignment during brush mounting, the second end including a second contact surface adapted to contact the second mounting support, and the second contact surface having a spherical profile so as to form a spherical joint between the second end of

the mandrel and the second mounting support that compensates for mounting assembly misalignment during brush mounting.

Claim 22 (Original): The mandrel of claim 21, wherein the first contact surface has a concave shape adapted to mate with a convex portion of the first mounting support.

Claim 23 (Original): The mandrel of claim 21, wherein the first contact surface has a convex shape adapted to mate with a concave portion of the first mounting support.

Claim 24 (Original): The mandrel of claim 23, wherein the second contact surface has a concave shape adapted to mate with a convex portion of the second mounting support.

Claim 25 (Original): The mandrel of claim 21, further comprising a spring mounted in the body and adapted to bias at least one of the ends against a corresponding mounting support.

Claim 26 (Currently amended): A mounting assembly for a wafer-scrubber brush, comprising:

    a bearing;  
    a brush support rotatably mounted on the bearing and having an outer end adapted to couple to a brush mandrel; and  
    a flexure flexible coupling adapted to flexibly mount the bearing to a mounting member.

Claim 27 (Original): The mounting assembly of claim 26, wherein the outer end of the brush support includes a contact surface adapted to contact the brush mandrel, the contact surface having a spherical profile.

Claim 28 (Currently amended): The mounting assembly of claim 26, further comprising:

    a housing in which the bearing is mounted; and  
    a second bearing mounted in the housing;  
    the housing being mounted on the flexure flexible coupling.

Claim 29 (New): A mounting assembly for a wafer-scrubber brush, comprising:

    a mounting member adapted to be mounted to a wall of a wafer scrubbing device;

    a bearing secured to the mounting member; and

    a brush support rotatably mounted on the bearing and having an outer end that includes a contact surface adapted to contact a brush mandrel, the contact surface having a spherical profile;

    wherein the outer end of the brush support includes an extension member that extends outwardly beyond the contact surface and is adapted to limit rotational motion of the outer end of the brush support relative to the brush mandrel.